

09/680 286



In response to the Advisory Action mailed 2/12/04, please amend the above application as follows:

### **Proposed Response**

#### **AMENDMENT – Claims**

This listing of claim(s) will replace all prior versions, and listings, of claims in the application:

##### **Listing of Claims:**

Cancel claims 18-33

Claims 1-33 (canceled)

Add new claim 34 as follows:

Claim 34 (New) An apparatus for measuring parameters used in manufacturing an integrated circuit or a micromechanical device in microelectronic processing without evasive interruptions to manufacturing equipment, the parameters selected from the group consisting of temperature, liquid and gas flow rate, distance, particles, humidity, pressure, viscosity, radiation, velocity, density, acceleration, stress/strain, pH, and the parameters determined using techniques selected from the group consisting of Energy Dispersive x-ray Spectroscopy (EDS), Cathodoluminescence (CL), X-ray Photoelectron Spectroscopy (XPS), Ultraviolet Photoelectron Spectroscopy (UPS), Auger, Electron Spectroscopy (AES), Reflection High Energy Electron Diffraction (REELS), X-ray Fluorescence (XRF), Photoluminescence (PL), Modulation Spectroscopy, Variable Angle Spectroscopic Ellipsometry (VASE), Fourier Transform Infrared Spectroscopy (FTIR),

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Title: REMOTE MONITORING OF CRITICAL PARAMETERS FOR CALIBRATION OF MANUFACTURING EQUIPMENT AND FACILITIES

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